

METHOD FOR COMPENSATING THE POSITION OFFSET
OF A CAPACITIVE INERTIAL SENSOR, AND CAPACITIVE INERTIAL SENSOR

ABSTRACT OF THE DISCLOSURE

An inertial sensor having a stator and a rotor made of semiconductor material and electrostatically coupled together, and a microactuator also made of semiconductor material, coupled to the rotor and controlled so as to move the rotor itself and thus compensate for the position offset thereof.

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